

## Electronic Supplementary Information

# Analytical figures of merit of a low-dispersion aerosol transport system for high-throughput LA-ICP-MS analysis

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## 1. Tables

### 1.1. Table S1

**Table S1.** List of predicted average fluid velocities, Reynolds numbers and pressure drops for aerosol transport tubing of varying length and ID.

<b>Length (m)</b>	<b>ID (mm)</b>	<b>v<sub>avg</sub> (m s<sup>-1</sup>)</b>	<b>Re (-)</b>	<b> ΔP  (mbar)</b>
0.50	0.75	17.2	109	100
0.50	1.00	10.3	87	33
0.50	2.00	2.6	45	2
0.75	0.75	16.5	105	147
0.75	1.00	10.1	86	49
0.75	2.00	2.6	45	3
1.00	0.75	15.9	101	192
1.00	1.00	10.0	85	64
1.00	2.00	2.6	45	4
1.50	0.75	14.8	94	277
1.50	1.00	9.7	82	95
1.50	2.00	2.6	45	6
3.00	0.75	12.6	80	505
3.00	1.00	9.0	76	183
3.00	2.00	2.6	44	12

## 1.2. Table S2

**Table S2.** Instrument settings and data acquisition conditions for evaluating the influence of tubing ID, length and curvature on the analytical performance of aerosol transport systems.

<b>Analyte G2 193 nm ArF*excimer-based LA-unit with HelEx-II ablation chamber</b>					
	<b>Standard ATS PTFE tubing 4 mm OD 2 mm ID 3 m length</b>	<b>Standard ATS PTFE tubing 4 mm OD 2 mm ID 1 m length</b>	<b>Improved ATS PTFE tubing 2 mm OD 1.3 mm ID 0.75 m length</b>	<b>ARIS PEEK tubing 1/16" OD 0.04" ID 3 m length</b>	<b>ARIS PEEK tubing 1/16" OD 0.03" ID 0.9 m length</b>
Laser energy density (J cm <sup>-2</sup> )	3.5	3.5	3.5	3.5	3.5
Repetition rate (Hz)	1	5	10	1	5
Lateral scan speed (μm s <sup>-1</sup> )	20	100	200	20	50
Beam waist diameter (μm)	20	20	20	20	10
Dosage (shots position <sup>-1</sup> )	1	1	1	1	1
He carrier gas flow rate (L min <sup>-1</sup> )	0.85	0.65	0.65	0.49	0.60
ICP-mass spectrometer	iCAP Q	XSeries-II	XSeries-II	iCAP Q	Agilent 7900
RF power (W)	1240	1350	1350	1240	1500
Ar plasma gas flow rate (L min <sup>-1</sup> )	14.0	13.0	13.0	14.0	15.0
Ar auxiliary gas flow rate (L min <sup>-1</sup> )	1.00	0.70	0.70	1.00	0.90
Ar make-up gas flow rate (L min <sup>-1</sup> )	0.70	0.69	0.69	0.70	1.02
Acquired m/z ratio (amu)	238	238	238	238	238
Respective dwell times (ms)	10	2	2	0.5	1
Total scan cycle time (ms)	10	2	2	0.5	1

## 1.3. Table S3

**Table S3.** Instrument settings and data acquisition conditions for evaluating the analytical performance of the ARIS and standard ATS in combination with a 2<sup>nd</sup> generation two-volume ablation cell.

<b>Analyte G2 193 nm ArF*excimer-based LA-unit with HelEx-II ablation chamber</b>		
	<b>Standard ATS</b>	<b>ARIS</b>
Laser energy density (J cm <sup>-2</sup> )	3.5	3.5
Repetition rate (Hz)	1	1
Lateral scan speed (μm s <sup>-1</sup> )	20	20
Beam waist diameter (μm)	20	20
Dosage (shots position <sup>-1</sup> )	1	1
He carrier gas flow rate (L min <sup>-1</sup> )	0.85	0.49
<b>Thermo iCAP Q ICP-mass spectrometer</b>		
RF power (W)	1240	1240
Ar plasma gas flow rate (L min <sup>-1</sup> )	14.0	14.0
Ar auxiliary gas flow rate (L min <sup>-1</sup> )	1.00	1.00
Ar make-up gas flow rate (L min <sup>-1</sup> )	0.70	0.70
Acquired m/z ratio (amu)	238	238
Respective dwell times (ms)	10	0.5
Total scan cycle time (ms)	10	0.5

## 1.4. Table S4

**Table S4.** Instrument settings and data acquisition conditions for evaluating the analytical performance of the ARIS across a wide range of laser beam sizes.

<b>Analyte G2 193 nm ArF*excimer-based LA-unit with HelEx-II ablation chamber + ARIS</b>	
Laser energy density (J cm <sup>-2</sup> )	3.5
Repetition rate (Hz)	1
Lateral scan speed (μm s <sup>-1</sup> )	10-110
Beam waist diameter (μm)	10-110
Dosage (shots position <sup>-1</sup> )	1
He carrier gas flow rate (L min <sup>-1</sup> )	0.6
<b>Agilent 7900 ICP-mass spectrometer</b>	
RF power (W)	1500
Ar plasma gas flow rate (L min <sup>-1</sup> )	15.0
Ar auxiliary gas flow rate (L min <sup>-1</sup> )	0.90
Ar make-up gas flow rate (L min <sup>-1</sup> )	1.00
Acquired m/z ratio (amu)	238
Respective dwell times (ms)	4
Total scan cycle time (ms)	4

## 1.5. Table S5

**Table S5.** Instrument settings and data acquisition conditions for evaluating the analytical performance of the ARIS in combination with a 3<sup>rd</sup> generation low-dispersion ablation cell.

<b>Iridia 193 nm ArF*excimer-based LA-unit with Cobalt ablation chamber + ARIS</b>	
Laser energy density (J cm <sup>-2</sup> )	4.0
Repetition rate (Hz)	50
Lateral scan speed (μm s <sup>-1</sup> )	250
Beam waist diameter (μm)	5
Dosage (shots position <sup>-1</sup> )	1
He carrier gas flow rate (L min <sup>-1</sup> )	0.7
<b>Agilent 7900 ICP-mass spectrometer</b>	
RF power (W)	1500
Ar plasma gas flow rate (L min <sup>-1</sup> )	15.0
Ar auxiliary gas flow rate (L min <sup>-1</sup> )	0.90
Ar make-up gas flow rate (L min <sup>-1</sup> )	1.00
Acquired m/z ratio (amu)	238
Respective dwell times (ms)	0.1
Total scan cycle time (ms)	0.1

## 1.6. Table S6

**Table S6.** Instrument settings and data acquisition conditions for evaluating laser-induced elemental fractionation and oxide formation at high laser repetition rates

<b>Iridia 193 nm ArF*excimer-based LA-unit with Cobalt ablation chamber + ARIS</b>		
	<b>U<sup>+</sup>/Th<sup>+</sup> evaluation</b>	<b>UO<sup>+</sup>/U<sup>+</sup> evaluation</b>
Laser energy density (J cm <sup>-2</sup> )	4.0	4.0
Repetition rate (Hz)	50-1000	50-1000
Lateral scan speed (μm s <sup>-1</sup> )	12.5-250	12.5-250
Beam waist diameter (μm)	5	5
Dosage (shots position <sup>-1</sup> )	20	20
He carrier gas flow rate (L min <sup>-1</sup> )	0.7	0.7
<b>Agilent 7900 ICP-mass spectrometer</b>		
RF power (W)	1500	1500
Ar plasma gas flow rate (L min <sup>-1</sup> )	15.0	15.0
Ar auxiliary gas flow rate (L min <sup>-1</sup> )	0.90	0.90
Ar make-up gas flow rate (L min <sup>-1</sup> )	1.00	1.00
Acquired m/z ratios (amu)	232 & 238	238 & 254
Respective dwell times (ms)	98 & 98	98 & 98
Total scan cycle time (ms)	200	200

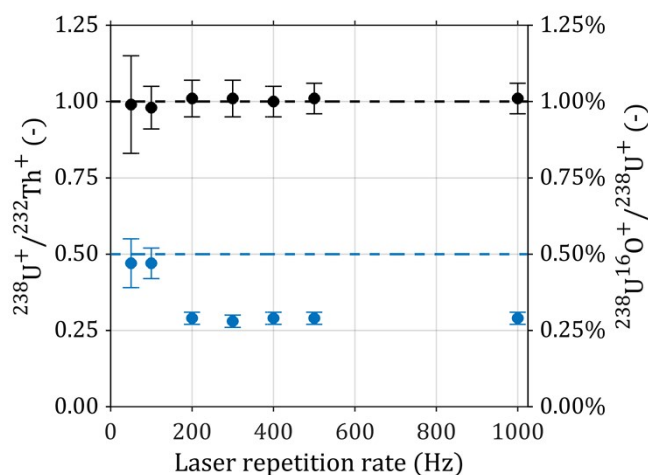
## 1.7. Table S7

**Table S7.** Instrument settings and data acquisition conditions for evaluating the analytical performance of the ARIS and Cobalt ablation chamber across a wide range of laser repetition rates.

<b>Iridia 193 nm ArF*excimer-based LA-unit with Cobalt ablation chamber + ARIS</b>	
Laser energy density (J cm <sup>-2</sup> )	4.0
Repetition rate (Hz)	10-1000
Lateral scan speed (μm s <sup>-1</sup> )	2.5-250
Beam waist diameter (μm)	5 (square mask)
Dosage (shots position <sup>-1</sup> )	1
He carrier gas flow rate (L min <sup>-1</sup> )	0.7
<b>Agilent 7900 ICP-mass spectrometer</b>	
RF power (W)	1500
Ar plasma gas flow rate (L min <sup>-1</sup> )	15.0
Ar auxiliary gas flow rate (L min <sup>-1</sup> )	0.90
Ar make-up gas flow rate (L min <sup>-1</sup> )	1.00
Acquired m/z ratio (amu)	238
Respective dwell times (ms)	0.1
Total scan cycle time (ms)	0.1

## 2. Figures

## 2.1. Figure S1

**Figure S1.** The average  $^{238}\text{U}^+ / ^{232}\text{Th}^+$  (black circles) and  $^{238}\text{U}^{16}\text{O}^+ / ^{238}\text{U}^+$  ratios (blue circles) with corresponding standard deviations obtained upon ablation of a NIST SRM 610 glass using a square spot size of 5 μm across the full range of laser repetition rates.